

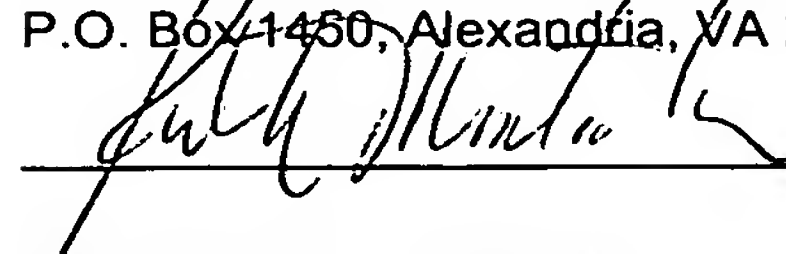
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/ Ruth Montalvo Date: 12/22/05

Customer No. 026418

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney's Docket No.: JG-SU-5221/500577.20071

U.S. Application No.:

International Application No.: PCT/JP2004/015999

International Filing Date: OCTOBER 28, 2004

28 OCTOBER 2004

Priority Date Claimed: DECEMBER 10, 2003

10 DECEMBER 2003

Title of Invention: PROCESSING METHOD OF SILICON WAFER

Applicant(s) for (DO/EO/US): Sakae KOYATA and Kazushige TAKAISHI

Mail Stop PCT
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-450

INFORMATION DISCLOSURE STATEMENT

S I R:

Applicant herewith submits together with the simultaneously filed National Phase application of PCT/JP2004/015999, a copy of the International Search Report (PCT/ISA/210) dated February 15, 2005 citing some of the following references:

	Document Number	Date	Name and/or Country	English Translation and/or Equivalent
AA	5,340,437	08/23/1997	Erk, et al.	
AB	6,239,039	05/29/2001	Nihonmatsu, et al.	
AC	6,346,485	02/12/2002	Nihonmatsu	
AD	2003/0171075	09/11/2003	Nihonmatsu, et al.	
AL	8-502148	05/08/1996	Japan	
AM	11-135474	05/21/1999	Japan	Abstract only
AN	11-233485	08/27/1999	Japan	Abstract only
AO	2002-203823	07/19/2002	Japan	Abstract only
AP	2003-100701	04/04/2003	Japan	Abstract only

Accompanying this Information Disclosure Statement and form PTO-1449 are copies of the documents including English Abstract and US equivalent. Document AN is mentioned on page 3 of the substitute specification.

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The USPTO waived the requirement under 37 C.F.R. §1.98(a)(2)(i) for submitting copies of US patents and US patent application publications in all U.S. applications filed after June 30, 2003. First pages of US documents only.

IAP20 RECEIVED 22 DEC 2005


This submission is not an admission that the information disclosed in the documents is material to the patentability of the invention disclosed and/or claimed in the above-identified application.

Respectfully submitted,

JEG:ram
08/10/05
Tel. (212) 521-5400

Enclosures:

Search Report (PCT/ISA/210);
PTO-1449
4 first pages US Patents
5 foreign documents w/English Abstracts


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LIST OF PRIOR ART CITED BY APPLICANT
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Docket No. JG-SU-5221/500577.20071
Applicant(s): Sakae KOYATA and Kazushige TAKAISHI
Application No. (Int'l Appln No. PCT/JP2004/015999 28OCT04) Group:
Filed: Examiner:

U.S. PATENT DOCUMENTS

Exam. Init		Document Number	Date	Name	Class	Sub-Class	Filing Date Appropriate
	AA	5,340,437	08/23/1997	Erk, et al.			
	AB	6,239,039	05/29/2001	Nihonmatsu, et al.			
	AC	6,346,485	02/12/2002	Nihonmatsu			
	AD	2003/0171075	09/11/2003	Nihonmatsu, et al.			
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	CLASS	Sub-Class	Translation YES NO
	AL	8-502148	05/08/1996	Japan			
	AM	11-135474	05/21/1999	Japan			Abstract only
	AN	11-233485	08/27/1999	Japan			Abstract only
	AO	2002-203823	07/19/2002	Japan			Abstract only
	AP	2003-100701	04/04/2003	Japan			Abstract only
	AQ						
	AR						
	AS						
	AT						

OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)

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	AY	
	AZ	

Examiner:	Date:
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.